

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application

Inventor(s): Jeffrey W. Carr

Appln. No.: 10/608,384

Confirm. No.: 7970

Filed: June 27, 2003

Title: Apparatus and Method for Reactive Atom
Plasma Processing for Material Deposition

PATENT APPLICATION

Art Unit: 1765

Examiner: Vinh, Lan

Docket No. RAPT-01000US4

Customer No. 23910

**AMENDMENT AND REPLY TO OFFICE
ACTION UNDER 37 C.F.R. § 1.111**

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

INTRODUCTORY COMMENTS

This Reply is in response to the Office Action dated April 26, 2007.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 4 of this paper.